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Date	Client/Matter Number
November 23, 2004	100806-00233
From	Attorney Number
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Total number of pages, including cover letter: 5  
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### Comments

U.S. Patent Application No.: 10/657,429

ELECTRON BEAM EXPOSURE MASK, ELECTRON BEAM EXPOSURE METHOD, METHOD OF FABRICATING SEMICONDUCTOR DEVICE, AND ELECTRON BEAM EXPOSURE APPARATUS

Our Reference No.: NECF 17.638B (100806-00233)

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COMMENTS ON STATEMENT OF REASON FOR ALLOWANCE

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41321829.01



Attorney Docket No.: NECF 17.638B (100806-00233)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Inventor** : **Mami Miyasaka**  
**Title** : **ELECTRON BEAM EXPOSURE MASK, ELECTRON  
BEAM EXPOSURE METHOD, METHOD OF  
FABRICATING SEMICONDUCTOR DEVICE, AND  
ELECTRON BEAM EXPOSURE APPARATUS**  
**Serial No.** : **10/657,429**  
**Confirmation No.** : **9031**  
**Filed** : **09/08/2003**  
**Examiner** : **Anthony G. Quash**  
**Group Art Unit** : **2881**

Mail Stop: Issue Fee  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**Comments on Statement of Reasons for Allowance**

Sir:

The referenced application was allowed on, August 26, 2004. The issue fee due on November 26, 2004 is being paid concurrently herewith.

Applicant hereby acknowledges the Examiner's Reasons for Allowance. Applicant respectfully notes that there may be additional reasons for allowance that have not been specifically cited, and which may apply to various of the allowed claims, in addition to or instead of the cited reasons. Applicant respectfully suggests that notwithstanding the Examiner's

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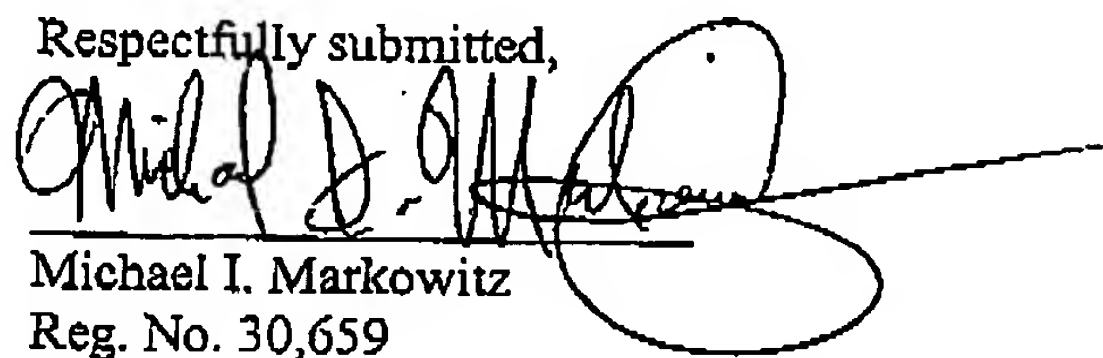


Reasons for Allowance, it is believed that each of the allowed claims is patentable in its own right and/or for other reasons raised during the prosecution and/or explained in the specification of this application.

To the extent that any statements regarding patentability of any claims allowed by the Examiner made by the Applicant or the Examiner in any document filed in this application are inconsistent with or not included in the Examiner's Reasons for Allowance, they are incorporated by reference herein.

Any fee due with this paper may be charged on Deposit Account No. 50-1290.

Respectfully submitted,



Michael I. Markowitz  
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Date: November 23, 2004  
Docket No.: NECF 17.638B (100806-00233)

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